

DETAILED ACTION

Response to Arguments

1. Applicant's arguments, filed 2/26/2008, with respect to the 35 USC 103(a) rejection has been fully considered and are persuasive. The examiner has withdrawn the rejection for the reasons set forth in the Remarks section dated 2/26/2008.

EXAMINER'S AMENDMENT

2. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it **MUST** be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Daniel Hu on 4/23/2008.

The application has been amended as follows:

IN THE CLAIMS

In claim 29, line 4-5, after "amorphous film during the source supply process;" please insert "

supplying, during a second process, H₂ but not SiH₄ to the chamber;"

In claim 29, line 6, after "depositing the microcrystalline thin film on the substrate" please replace ", wherein prior to depositing the microcrystalline thin film, the supplying of SiH₄ to the chamber is stopped" with " during the second process"

In claim 30, line 4, please delete "wherein depositing the microcrystalline thin film is performed during a source depositing process, and "

In claim 30, line 5-6, please replace "source depositing" with "second"

In claim 31, line 2, after "supplying" please insert ",during a first process,"

In claim 31, line 2, after "substrate is located;" please insert " supplying, during a second process, H₂ but not SiH₄ to the chamber;"

In claim 31, line 3, after "depositing the microcrystalline thin film on the substrate" please replace ", wherein prior to depositing the microcrystalline thin film, the supplying of SiH₄ to the chamber is stopped" with " during the second process"

Allowable Subject Matter

3. Claims 1, 3-8, 10, 12-14, 17-18, and 26-31 are allowed.
4. The following is an examiner's statement of reasons for allowance:

5. The claims are allowed for the same reasons as set forth in the office action dated 8/15/2007 and substantially for the reasons set forth in the Remarks dated 2/26/2008. In summation, the examiner, after reviewing the prior art of record, finds the applicants' reasoning persuasive. The prior art applied in the office action dated 10/26/2007 discloses supplying SiH_4 and H_2 in a ratio so as to not deposit an amorphous thin film, however, none of the references alone or in combination teaches or makes obvious supplying, during a second process, H_2 but not SiH_4 to the chamber and depositing the microcrystalline thin film during this second supplying process. The combination of prior art applied 10/26/2007 is deficient in this regard for the reasons set forth by applicant in Remarks dated 2/26/2008.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to DAVID TUROCY whose telephone number is (571)272-2940. The examiner can normally be reached on Monday-Friday 8:30-6:00, No 2nd Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Timothy Meeks, can be reached on (571) 272-1423. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Art Unit: 1792

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

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